Advertisement for the post of Research Associate (RA) positions in the project of MEMS based Piezo Sensors and Bio Sensors

Date of Advertisement: 11/01/2024

Applications are invited from the Indian nationals for the post of Research Associate in the area of Micromachining and MEMS with relevant prior experience.

Name of the post	Research Associate (RA)
Number of vacancies	2
Sponsored Project	*Fabrication of high temperature piezo pressure sensor for Aeronautical applications* *And* *Bio-Sensor fabrication and testing for real time applications*
Salary	Consolidated based on the Experience (Rs.45000 to Rs.55000)
Appointment period	6 months (extendable up to the closure of project.) Note: 1. Monthly fellowship will be released after monthly progress review report. 2. In case of unsatisfactory progress, the candidate may be asked to leave after giving one-month notice.
Essential Qualification	1. PhD with **BE/BTech/MTECH/Equivalent** in /EE/**Physics/Biotech/other relevant branches** with research (1) focus in the area of MEMS fabrication. Candidate with relevant experience and publication in standard MEMS journals will have added advantage. (2) focus in the area of Bio Sensors. Candidate with relevant experience and publication in standard Bio Sensors journals will have added advantage. 2. Candidate should have good academic records throughout and good writing skills.
Age limit:	Maximum 45 years as on the day on which the application is made.
Job Description	- Collection of relevant literatures

	- Microfabrication processes such as wafer cleaning, thin film deposition, photolithography, wafer bonding, etching of silicon and glass wafers. - Characterization of microstructures using different tools such as SEM, Ellipsometry, optical microscope..etc - Expertise in TCAD tools - Report preparation and lab management. - Interaction with sponsored agencies, .
Application Procedure	Candidates are required to send following documents in a **single pdf** file 1. Latest CV with marks percentage, experience, and a list of patents and publications. 2. Statement of purpose stating relevant experience towards the project. to Email: satish.bonam@ee.iith.ac.in with subject line "Application for RA positions in the Project MEMS based Piezo pressure sensors" /Bio *Sensor fabrication and testing for real time applications* as early as possible
Selection Procedure	Candidates will be shortlisted based on the eligibility criteria, academic record, and relevant experience. Only, shortlisted candidates will be intimated through email for the online interview by the selection committee. Merely meeting the criteria may not guarantee a call for an interview. The position will be left vacant and new advertisement with extended date will be given if no suitable candidate is found.

For more details about our work, please visit Shiv Govind Singh | IIT Hyderabad

Contact Person: Prof. Shiv Govind Singh, Department of Electrical Engineering, Indian Institute of Technology,Hyderabad, Kandi, 502285, Sangareddy, TS, India